

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Accompanying Continuation Application under 37 CFR 1.53:

Prior Application: T. TANAKA et al  
Serial No. 09/810,194  
Filed: March 19, 2001  
Group Art Unit: 1756  
Examiner: K. Sagar

For: AN ELECTRON DEVICE MANUFACTURING METHOD,  
A PATTERN FORMING METHOD, AND A PHOTOMASK  
USED FOR THOSE METHODS

PRELIMINARY AMENDMENT

Commissioner for Patents  
Alexandria, VA 22313

Sir:

Prior to examination, please amend the above application  
as follows.